Vaksis Vacuum Systems Bulletin Year: 7, No: 21, October 2017

PVD AND CVD COATING SYSTEMS FOR VARIOUS APPLICATIONS

www.vaksis.com



CVD: Chemical Vapor Deposition

fingerprint detection system

new product MiDAS/PVD-4T PVD-3T Small

activities

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new product -

MIDAS®

MiDAS/ PVD-4T

The system is designed to deposit Zn, Au, Al, Ag etc. on various substrates including plastic, paper, and leather.

The system includes four thermal evaporation sources. It is equipped with two electrical power sources and two in-situ thickness monitors.



Base Pressure: < 2x10⁻⁷ Torr

Chamber: Stainless steel prismatic

Substrate Size: 60x75 cm cylindrical rotating

holder and 50x60 cm concave holder

In-situ Thickness Measurement: with Quartz

X-tal Oscillator

Control: Fully Automatic







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new product PVD-3T Small

The system is particularly designed to deposit Zn, Au, Al, Ag, etc. on various substrates including plastic, paper, and leather.

The system includes three thermal evaporation sources, one electrical power source, and one in-situ thickness monitor.



Technical Specifications

Base Pressure: < 1x10⁻⁵ Torr

Chamber: Stainless steel and prismatic

Substrate Size: can hold thin flexible substrates

with the dimension of 21 cm x 30 cm

In-situ Thickness Measurement: with Quartz

X-tal Oscillator

Control: Fully Automatic





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activities

which we will attend ...

BioEl 2018 International Winterschool on Bioelectronics, Tirol, Austria (10-17 March 2018)

http://www.jku.at/conferences/content/e216103/

BioEl 2018 will be held in Tirol, Austria between 10 - 17 March 2018.

Vaksis will be a sponsor of the winterschool and meet with the related participants on the exhibition area.

















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